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PATENT

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JUNE 24, 2004

Date

Carolyn L. Ross  
Carolyn L. Ross

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

*Fee Paid*

Appl. No. : 09/970,100                      Confirmation No. : 2699  
Applicants : Vishnu K. Agarwal and Scott G. Meikle  
Filed : October 2, 2001                      Attorney Docket No. : 500453.04  
Art Unit : 1762                      Customer No. : 27,076  
Examiner : William P. Fletcher  
Title : POLISHING PADS AND PLANARIZING MACHINES FOR MECHANICAL OR  
CHEMICAL-MECHANICAL PLANARIZATION OF MICROELECTRONIC-DEVICE  
SUBSTRATE ASSEMBLIES, AND METHODS FOR MAKING AND USING SUCH  
PADS AND MACHINES

**REQUEST FOR CONTINUED EXAMINATION (RCE)**  
**UNDER 37 C.F.R. § 1.114**

Mail Stop RCE  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

Applicant requests continued examination, under 37 C.F.R. § 1.114, of the above-identified application.

**1. Submission Required Under 37 C.F.R. § 1.114**

- a. ☐ Submission previously submitted
- i. ☐ Consider the amendment/reply under 37 C.F.R. § 1.116 previously filed on \_\_\_\_\_
- ii. ☐ Consider the arguments in the Appeal Brief or Reply Brief previously filed on \_\_\_\_\_

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01 FC:1202 108.00 DA  
02 FC:1201 86.00 DA